

LINE PRESSURE REGULATORS & SHUT OFF VALVES



LDPRR

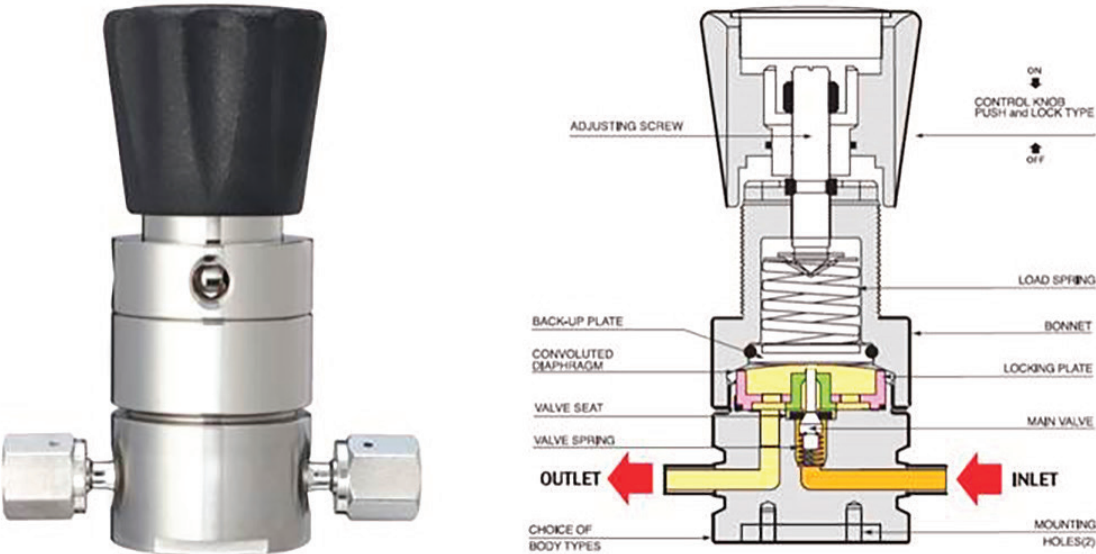
PRESSURE REGULATOR SERIES



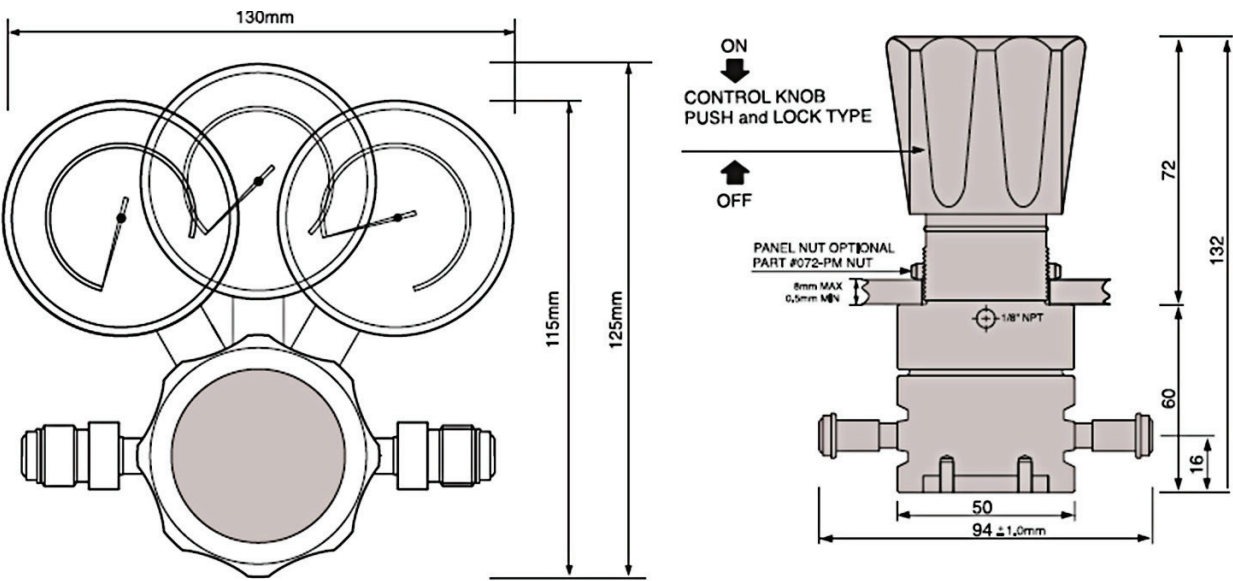
The LDPRR pressure regulator series is the pressure reducing regulator designed to use at the special manufacturing line of ultrahigh pure semi-conductors, bulk gas lines, and other facility lines. In order to use at the semi-conductor hook-up line, regulator's internal surface is treated to the level of E.P. 10Ra, 5Ra under B. A. grade. A special locking-plate system has developed and applied. All the process assembly, welding, testing and washing of this series is carried out and thoroughly managed in clean room.

Developed push and lock type handle which completely prevents the self-change of pre-set value which can be caused by the vibration from outside or minute vibration at the gas pipeline. You can prevent the self-changing of preset value just by pushing the handle and reset the value freely by drawing the handle.

FUNCTIONAL SCHEMATIC



DIMENSIONS



SPECIFICATIONS

VCR TYPE REGULATOR
DESIGNED FOR SEMICONDUCTOR APPLICATIONS
INTERNAL SURFACES B. A. GRADE TO E. P. 10 RA, 5 RA
ALL PERFORMED IN CLASS 100 AND CLASS 10 CLEAN-ROOMS
THREADLESS TYPE
LOCKING-PLATE SEAL SYSTEM

ORDERING INFORMATION

LDPRR	B	100	S	H	P	S	4MS	G1S
Series	Body material	Max outlet pressure	Diaphragm material	Max inlet pressure	Seat material	Flow capacity	Inlet/Outlet ports size	Gauge
Pressure reducing regulator for Ultra high purity series rated for semiconductor	B: Electropolish Stainless steel 316L 10Ra	100: 0.1-7 bar (1-100 psig)	S: Stainless Steel 316L	H: 3500 psig (238 bar)	P: PCTFE	S: Cv 0.06 standard 0-3000 psig, ¼"	4MS: ¼ Male VCR inlet/outlet	G1S: Gauge ¼" installed

LDMSV

ULTRA HIGH PURITY MANUAL SHUT OFF VALVE

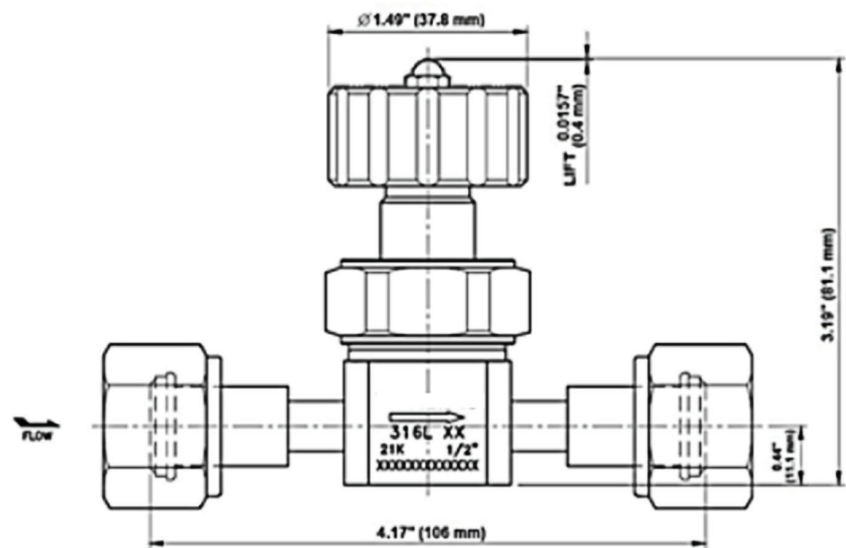


The LDMSV manual diaphragm shutoff valve series is specially designed for ultra high purity applications where sub ppb detection and trace analysis are required. This manual shut off valve can be mounted upfront the analytical devices/sensors or used for isolation/bypass lines mounted with purifiers/traps. They are also perfect to be mounted on the pressure regulators outlets and the sampling systems. Having a ¼ turn handle which interact on a diaphragm sealing makes it ideal for quick and precise shutoff without dead volume or leakage. The body is made of Stainless Steel 316L welded, and connections are face seal ¼ type to ensure the purity level.

SPECIFICATIONS

PRESSURE RATING	Vacuum to 290 psig (20 bar)
TEMPERATURE RATING	-9.4 °F ~ 149 °F (-23 °C ~ 65 °C)
FLOW COEFFICIENT	0.60
BODY MATERIAL	SS316L
DIAPHRAGM MATERIAL	Ni-Co Alloy
HANDLE MATERIAL	Aluminum (Blue) Handle shape provides visual identification of OPEN and CLOSED positions

DIMENSIONS



ORDERING INFORMATION

LDMSV	S	4FS
Series	Body material	Inlet/Outlet ports size
¼ turn diaphragm shutoff valve for Ultra high purity rated for semiconductor	S: Electropolish Stainless steel 316L	4FS: ¼ Female VCR inlet/outlet

LDPSV

ULTRA HIGH PURITY PNEUMATIC SHUT OFF VALVE

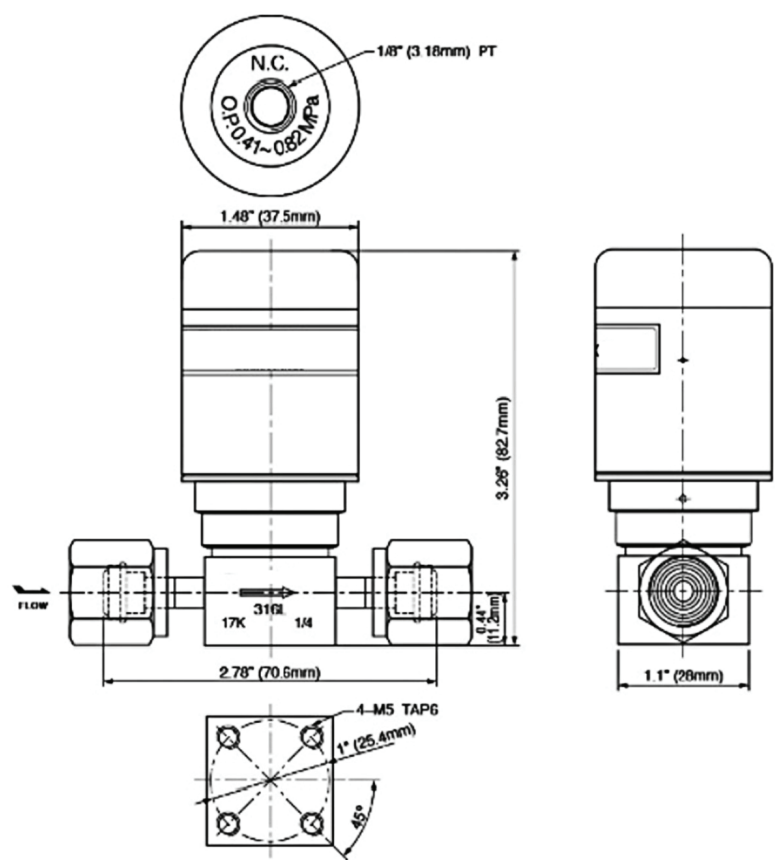


The pneumatic diaphragm shutoff valve series is specially designed for ultra high purity applications where sub ppb detection and trace analysis are required. This pneumatic shut off valve can be mounted upfront the analytical devices/sensors or used for isolation/bypass lines mounted with purifiers/traps. They are also perfect to be mounted on the pressure regulators outlets and the sampling systems. Having a pneumatic actuation which interact on a diaphragm sealing makes it ideal for quick and precise shutoff without dead volume or leakage for remote applications. Ideal for stream selector systems to be controlled remotely. The body is made of Stainless Steel 316L welded, and connections are face seal ¼ type to ensure the purity level. The valve can be configured with normally open or normally close position.

SPECIFICATIONS

PRESSURE RATING	250 psig (17.2 bar)	
TEMPERATURE RATING	-10 to 160 °F (-23 to 65 °C)	
FLOW COEFFICIENT	0.27	
PORT POSITION	NC or NO	
BODY MATERIAL	SS316L for Ultrahigh Purity Applications	
FULLY SWEEP FLOW PATH	Minimizes Entrapment Areas and Maximizes Flow Capacity	
FULLY CONTAINED PCTFE SEAT DESIGN PROVIDES:	<ul style="list-style-type: none">• Outstanding Resistance to Swelling and Contamination• Improved Helium Leak Test Performance• Minimal Particle Generation• Long Cycle Life	
DIAPHRAGM	<ul style="list-style-type: none">• Excellent in Strength and Corrosion Resistance• Optimal Design for Long Cycle Life	

DIMENSIONS



ORDERING INFORMATION

LDPSV	S	4FS	NC/NO
Series	Body material	Inlet/Outlet ports size	Port position
1/4 turn pneumatic diaphragm shutoff valve for Ultra high purity rated for semiconductor	S: Electropolish Stainless steel 316L	4FS: 1/4 Female VCR inlet/outlet	NC: Normally close position NO: Normally open position

